

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

in re Patent Application of

S. Y. LI et al.

Application No.: 09/820,695

Filed: March 30, 2001

For: METHOD OF PLASMA ETCHING

LOW-K DIELECTRIC MATERIALS

MAIL STOP AMENDMENT

Group Art Unit: 1763

Examiner: A. W. Olsen

Confirmation No.: 4162

## **AMENDMENT**

**Commissioner for Patents** P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed October 5, 2004, please amend the above-identified patent application as follows: